

PRESSURE SENSOR

ABSTRACT OF THE DISCLOSURE

A silicon pressure sensor includes a bossed diaphragm provided with a planar surface. The bossed diaphragm converts a pressure applied to the planar surface to a
5 force, and transmits the force through a central boss to a sensing diaphragm positioned next to the bossed diaphragm. The sensing diagram converts the force to an electrical signal. To fabricate the sensor, both diaphragms are formed in large numbers on silicon wafers and then bonded together before being separated as individual, complete sensors.

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